## **Electronic Supporting Information (ESI)**

## Continuous 3D Printing Quantum Dots-Based Electrodes for Lithium Storage with Ultrahigh Capacities

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## Characterizations

*Ink rheology:* Rheological properties of the ink were measured by using a stress controlled DHR-2 rheometer (TA Instruments) with a 20 mm steel flat plate geometry. The apparent viscosity of ink was carried out at an angular frequency from  $10^{-1}$  to  $10^2$  s<sup>-1</sup>. The storage (G') and loss (G") moduli of inks as a function of shear stress from  $10^{-1}$  to  $\sim 10^3$  Pa were obtain at a constant frequency of 1 Hz. Oscillatory time sweep with a constant shear rate of 1 Hz for 3 h was also carried out to demonstrate the structural stability of SnO<sub>2</sub> QDs/GO ink.

*3D printing:* First, as-prepared ink was loaded into a 3 mL syringes and extruded through a needle with a diameter of 200  $\mu$ m by air pressure, provided by an air-powered fluid dispenser (DSP501N, Fisnar). The SnO<sub>2</sub> quantum dots/graphene (3DP-SnO<sub>2</sub> QDs/G) architectures were printed onto a substrate controlled by a benchtop robot (Fisnar F4200n) with a pre-editing program of micro-lattices, which were designed with a center-to-center rods spacing (L) of 800  $\mu$ m and a rod diameter (d) of 200  $\mu$ m. The optimal extrusion pressure and move speed of nozzle were 60 psi and 8 mm s<sup>-1</sup>. Subsequently, the printed architectures were freeze-dried to remove the solvent and solidify the structure. Finally, a gas-based hydrazine hydrate reduction was implemented to reduce the GO.

## **Supplementary Figures**



Fig. S1. TEM and HRTEM images of the SnO<sub>2</sub> QDs.



Fig. S2. XRD patterns of 3DP-SnO<sub>2</sub> QDs/G and pure  $SnO_2$  QDs. The pure  $SnO_2$  QDs and 3DP-SnO<sub>2</sub> QDs/G shows the same characteristic peaks, which are indexed as tetragonal rutile-like  $SnO_2$ , confirming the presence of  $SnO_2$  in our printed architectures.



**Fig. S3.** a) AFM image of the SnO<sub>2</sub> QDs. b,c) Height analysis of the SnO<sub>2</sub> QDs along the blue and red line in a).



Fig. S4. a) TEM and b) HRTEM images of  $SnO_2$  QDs obtained in the absence of  $NH_4Cl$ .



Fig. S5. Digital images of the controllable sol-gel approach in the absence of  $SnCl_4$ . Only three-dimensional NH<sub>4</sub>Cl framework obtained after the freeze-drying process, and it decomposed after heat treatment.



Fig. S6. a) XPS and b) high resolution Sn 3d and O 1s spectra of SnO<sub>2</sub> QDs.



**Fig. S7.** a) The nitrogen adsorption-desorption isotherm and b) pore size distribution of SnO<sub>2</sub> QDs.



Fig. S8. Photos of 3DP-SnO<sub>2</sub> QDs/G architectures.



**Fig. S9.** Typical CV curves of 3DP-SnO<sub>2</sub> QDs/G architectures at a scan rate of 0.1 mV s<sup>-1</sup>. Two pairs of dominant redox peaks at 0.03 and 0.58 V, 1.05 V and 1.3 V are attributed to the alloy and dealloy of Sn metal and transformation between  $SnO_2$  and Sn, respectively.



**Fig. S10.** Electrochemical impedance spectra (EIS) of 3DP-SnO<sub>2</sub> QDs/G, SnO<sub>2</sub> QDs/G and SnO<sub>2</sub> QDs.



**Fig. S11.** The equivalent circuit diagram used for fitting the EIS profiles of 3DP-SnO<sub>2</sub> QDs/G, SnO<sub>2</sub> QDs/G and SnO<sub>2</sub> QDs. ( $R_1$ : the resistance of electrolyte;  $R_2$ : the resistance of the surface film formed on the electrodes;  $R_3$ : the charge-transfer resistance;  $CPE_1$ ,  $CPE_1$ : constant phase element;  $W_1$ : Warburg element)



**Fig. S12.** Cycle performances of 3DP-SnO<sub>2</sub> QDs/G architectures at a current density of 1A  $g^{-1}$ . A stable specific capacity of 187.4 mAh  $g^{-1}$  can be retained after 100 cycles.



**Fig. S13.** Comparison of CV curves of 3DP-SnO<sub>2</sub> QDs/G architectures with different printed layers.



**Fig. S14.** The specific capacities of 2-layer, 4-layer and 6-layer 3DP-SnO<sub>2</sub> QDs/G architectures. The 3DP-SnO<sub>2</sub> QDs/G with 6 layers shows slightly lower specific capacities than the samples with 2 layers and 4 layers.

Table S1. Kinetics parameters of 3DP-SnO<sub>2</sub> QDs/G, SnO<sub>2</sub> QDs/G and SnO<sub>2</sub> QDs architectures.

	3DP-SnO <sub>2</sub> QDs/G	SnO <sub>2</sub> QDs/G	SnO <sub>2</sub> QDs
$R_1[\Omega]$	6.8	6.5	3.9
$R_2[\Omega]$	19.9	11.0	8.3
$R_3 \left[\Omega ight]$	5.4	28.1	54.8